



*Jan*

PATENT  
Attorney Docket No. 02887.0270

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:	)	
	)	
Tadashi MITSUI	)	Group Art Unit: 2624
	)	
Application No.: 10/807,187	)	Examiner: David RASHID
	)	
Filed: March 24, 2004	)	
	)	
For: PATTERN MEASURING	)	Confirmation No.: 3737
APPARATUS, PATTERN	)	
MEASURING METHOD, AND	)	
MANUFACTURING METHOD OF	)	
SEMICONDUCTOR DEVICE	)	

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**RESPONSE TO INTERVIEW SUMMARY**

Applicants thank Examiner Rashid for taking the time to discuss the above-referenced application during a telephone interview held on July 16, 2008. During the interview, a proposed claim amendment was discussed in view of the applied references. No agreement was reached regarding the patentability of the claims.

Please grant any extensions of time required to enter this response and charge  
any additional required fees to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

Dated: September 2, 2008

By: Anthony J. Lombardi - Reg. No. 53,232  
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